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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Schultz, et al. ✓
Serial No.: 09/305,017 ✓
Filed: May 4, 1999 ✓
For: Illumination System Particularly
for EUV Lithography ✓
Art Unit: 2872
Examiner: Not Yet Assigned

Attorney Docket: 637.0001USP

Date: August 20, 1999

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In accordance with applicants' duty of disclosure under 37 C.F.R. §1.56, we are enclosing form PTO-1449 listing information that may be material to the patentability of this application, filed May 4, 1999.

We are enclosing a copy of the following patent, which is listed on form PTO-1449.

U.S. Patent No. 5,896,438 to Akira Miyake, et al, which issued April 20, 1999, titled X-Ray Optical Apparatus And Device Fabrication Method.

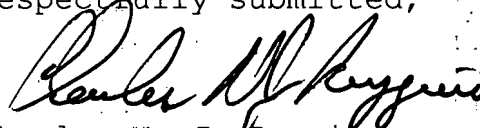
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It should be understood that attention has been called to the patent that has been deemed to be pertinent to the claimed present invention. In concluding what was pertinent, the criteria employed was considered most appropriate in light of the invention shown in the present patent. However, the Examiner or others may deem some other criteria to be just as appropriate or more appropriate. Therefore, the Examiner is respectfully urged to review the listed patent and to make the usual careful independent search for other prior art that may be pertinent.

Since this Supplemental Information Disclosure Statement is being submitted prior to the first Office Action on the merits, no petition or fee is required.

Applicants respectfully request favorable consideration and that this application be passed to allowance.

Respectfully submitted,



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